# WEST Search History

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DATE: Saturday, March 20, 2004

| Hide? | Set Name | Query | Hit Count |
|---|---|---|---|
| | | *DB=USPT; PLUR=YES; OP=ADJ* | |
| ☐ | L18 | L16 and rpm | 15 |
| ☐ | L17 | L16 and ipa | 3 |
| ☐ | L16 | L15 and rotat$ | 41 |
| ☐ | L15 | ((ultraso$ or megaso$) with nozzle) and 134/1.3 and wafer | 50 |
| ☐ | L14 | L11 and ((ultraso$ or megaso$) with nozzle) | 6 |
| ☐ | L13 | L10 and (ultraso$ or megaso$) | 1 |
| ☐ | L12 | L10 and ((ultraso$ or megaso$) with nozzle) | 1 |
| ☐ | L11 | (4401131\| 4985722\| 5061144\| 5081733\| 5092011\| 5144711\| 5213118\| 5226437\| 5236515\| 5261431\| 5278821\| 5282289\| 5297910\| 5327921\| 5345639\| 5370142\| 5375291\| 5498294\| 5503171\| 5509464\| 5520744\| 5626675\| 5651160\| 5730162\| 5927305\| 5975098\| 6021785)![pn] | 27 |
| ☐ | L10 | 6431184.pn. | 1 |
| ☐ | L9 | (tokyo electron).as. and ipa and rpm and ((heated or heating or temperature) with water) | 10 |
| ☐ | L8 | l7 and ipa | 3 |
| ☐ | L7 | (4401131\| 4985722\| 5061144\| 5081733\| 5092011\| 5144711\| 5213118\| 5226437\| 5236515\| 5261431\| 5278821\| 5282289\| 5297910\| 5327921\| 5345639\| 5370142\| 5375291\| 5498294\| 5503171\| 5509464\| 5520744\| 5626675\| 5651160\| 5730162\| 5927305\| 5975098\| 6021785)![pn] | 27 |
| ☐ | L6 | L2 and heated | 4 |
| ☐ | L5 | L2 and heating | 3 |
| ☐ | L4 | L2 and heat$ | 4 |
| ☐ | L3 | L2 and temperature | 4 |
| ☐ | L2 | (tokyo electron).as. and ipa and rpm and (ultraso$ or megaso$) | 5 |
| | | *DB=USOC; PLUR=YES; OP=ADJ* | |
| ☐ | L1 | 3062748.pn. | 1 |

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| ☐ | L14 | L11 and ((ultraso$ or megaso$) with nozzle) | 6 |
| ☐ | L13 | L10 and (ultraso$ or megaso$) | 1 |
| ☐ | L12 | L10 and ((ultraso$ or megaso$) with nozzle) | 1 |
| ☐ | L11 | (4401131| 4985722| 5061144| 5081733| 5092011| 5144711| 5213118| 5226437| 5236515| 5261431| 5278821| 5282289| 5297910| 5327921| 5345639| 5370142| 5375291| 5498294| 5503171| 5509464| 5520744| 5626675| 5651160| 5730162| 5927305| 5975098| 6021785)![pn] | 27 |
| ☐ | L10 | 6431184.pn. | 1 |
| ☐ | L9 | (tokyo electron).as. and ipa and rpm and ((heated or heating or temperature) with water) | 10 |
| ☐ | L8 | l7 and ipa | 3 |
| ☐ | L7 | (4401131| 4985722| 5061144| 5081733| 5092011| 5144711| 5213118| 5226437| 5236515| 5261431| 5278821| 5282289| 5297910| 5327921| 5345639| 5370142| 5375291| 5498294| 5503171| 5509464| 5520744| 5626675| 5651160| 5730162| 5927305| 5975098| 6021785)![pn] | 27 |
| ☐ | L6 | L2 and heated | 4 |
| ☐ | L5 | L2 and heating | 3 |
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| ☐ | L2 | (tokyo electron).as. and ipa and rpm and (ultraso$ or megaso$) | 5 |
| | | *DB=USOC; PLUR=YES; OP=ADJ* | |
| ☐ | L1 | 3062748.pn. | 1 |

END OF SEARCH HISTORY

Day :
Saturday
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3/20/2004

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## PALM INTRANET

# Inventor Name Search Result

Your Search was:

Last Name = VERHAVERBEKE
First Name = STEVEN

| Application# | Patent# | Status | Date Filed | Title | Inventor Name 51 |
|---|---|---|---|---|---|
| 60450117 | Not Issued | 020 | 02/25/2003 | DILUTE SULFURIC PEROXIDE AT POINT-OF-USE | VERHAVERBEKE, STEVEN |
| 60434188 | Not Issued | 020 | 12/16/2002 | SINGLE WAFER CLEANING METHOD TO REDUCE PARTICLE DEFECTS ON A WAFER SURFACE | VERHAVERBEKE, STEVEN |
| 60270815 | Not Issued | 159 | 02/23/2001 | METHOD FOR ETCHING ELECTRONIC COMPONENTS CONTAINING TANTALUM | VERHAVERBEKE, STEVEN |
| 60214116 | Not Issued | 159 | 06/26/2000 | CLEANING METHOD AND SOLUTION FOR CLEANING A WAFER IN A SINGLE WAFER PROCESS | VERHAVERBEKE, STEVEN |
| 60214115 | Not Issued | 159 | 06/26/2000 | FULL WAFER MEGA SONICS COVERAGE | VERHAVERBEKE, STEVEN |
| 60214073 | Not Issued | 159 | 06/26/2000 | METHOD AND APPARATUS FOR REMOVING ADHERED MOISTURE FROM A WAFER | VERHAVERBEKE, STEVEN |

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| 60214058 | Not Issued | 159 | 06/26/2000 | METHOD AND APPARATUS FOR DISSOLVING A GAS INTO A LIQUID FOR SINGLE WET WAFER PROCESSING | VERHAVERBEKE, STEVEN |
|---|---|---|---|---|---|
| 60214057 | Not Issued | 159 | 06/26/2000 | METHOD AND APPARATUS FOR FRONTSIDE AND BACKSIDE WET PROCESSING OF A WAFER | VERHAVERBEKE, STEVEN |
| 60214056 | Not Issued | 159 | 06/26/2000 | METHOD AND APPARATUS FOR CHEMICAL MIXING IN A SINGLE WAFER PROCESS | VERHAVERBEKE, STEVEN |
| 60214055 | Not Issued | 159 | 06/26/2000 | WAFER SPRAY CONFIGURATIONS FOR A SINGLE WAFER PROCESSING APPARATUS | VERHAVERBEKE, STEVEN |
| 60214054 | Not Issued | 159 | 06/26/2000 | ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS | VERHAVERBEKE, STEVEN |
| 60188895 | Not Issued | 159 | 03/13/2000 | APPARATUS AND PROCESSES FOR REMOVING BULK PHOTORESIST | VERHAVERBEKE, STEVEN |
| 60168487 | Not Issued | 159 | 12/02/1999 | APPARATUS FOR PROVIDING OZONATED PROCESS FLUID AND METHODS FOR USING SAME | VERHAVERBEKE, STEVEN |
| 60020397 | Not Issued | 159 | 06/25/1996 | METHOD FOR SULFURIC ACID RESIST STRIPPING | VERHAVERBEKE, STEVEN |
| 10676182 | Not Issued | 020 | 09/30/2003 | DILUTE SULFURIC PEROXIDE AT POINT-OF-USE | VERHAVERBEKE, STEVEN |
| 10637725 | Not | 020 | 08/07/2003 | METHOD AND | VERHAVERBEKE, |

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| | | | | | |
|---|---|---|---|---|---|
| | Issued | | | APPARATUS FOR DISSOLVING A GAS INTO A LIQUID FOR SINGLE WET WAFER PROCESSING | STEVEN |
| 10616093 | Not Issued | 020 | 07/08/2003 | ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS | VERHAVERBEKE, STEVEN |
| 10407953 | Not Issued | 030 | 04/04/2003 | GUTTER AND SPLASH-GUARD FOR PROTECTING A WAFER DURING TRANSFER FROM A SINGLE WAFER CLEANING CHAMBER AND POSITIONING SUCH A WAFER IN THIS SINGLE WAFER CHAMBER | VERHAVERBEKE, STEVEN |
| 10407692 | Not Issued | 030 | 04/03/2003 | ROTATIONAL THERMOPHORETIC DRYING | VERHAVERBEKE, STEVEN |
| 10394465 | Not Issued | 041 | 03/21/2003 | USING SUPERCRITICAL FLUIDS AND/OR DENSE FLUIDS IN SEMICONDUCTOR APPLICATIONS | VERHAVERBEKE, STEVEN |
| 10366103 | Not Issued | 030 | 02/12/2003 | METHOD AND APPARATUS FOR WAFER CLEANING | VERHAVERBEKE, STEVEN |
| 10349591 | Not Issued | 030 | 01/22/2003 | RATE MONITOR FOR WET WAFER CLEANING | VERHAVERBEKE, STEVEN |
| 10229446 | Not Issued | 030 | 08/27/2002 | METHOD AND APPARATUS FOR PROCESSING A WAFER | VERHAVERBEKE, STEVEN |
| 10194605 | Not Issued | 161 | 07/12/2002 | METHOD AND COMPOSITION FOR CHEMICAL POLISHING | VERHAVERBEKE, STEVEN |

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| 10188174 | Not Issued | 061 | 07/01/2002 | USING A TIME CRITICAL WAFER CLEANING SOLUTION BY COMBINING A CHELATING AGENT WITH AN OXIDIZER AT POINT-OF-USE | VERHAVERBEKE, STEVEN |
|---|---|---|---|---|---|
| 10187571 | Not Issued | 030 | 07/01/2002 | POINT-OF-USE MIXING WITH H2SO4 AND H2O2 ON TOP OF A HORIZONTALLY SPINNING WAFER | VERHAVERBEKE, STEVEN |
| 10121635 | Not Issued | 030 | 04/11/2002 | METHOD AND APPARATUS FOR WAFER CLEANING | VERHAVERBEKE, STEVEN |
| 10113495 | Not Issued | 041 | 03/29/2002 | GUTTER AND SPLASH-GUARD FOR PROTECTING A WAFER DURING TRANSFER FROM A SINGLE WAFER CLEANING CHAMBER | VERHAVERBEKE, STEVEN |
| 10097853 | Not Issued | 041 | 03/12/2002 | METHODS AND APPARATUSES FOR DRYING WAFER | VERHAVERBEKE, STEVEN |
| 10074516 | Not Issued | 041 | 02/13/2002 | METHOD FOR ETCHING ELECTRONIC COMPONENTS CONTAINING TANTALUM | VERHAVERBEKE, STEVEN |
| 09945454 | Not Issued | 071 | 08/31/2001 | METHOD AND APPARATUS FOR PROCESSING A WAFER | VERHAVERBEKE, STEVEN |
| 09892130 | Not Issued | 071 | 06/25/2001 | ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS | VERHAVERBEKE, STEVEN |
| 09891989 | Not Issued | 161 | 06/25/2001 | CHUCK FOR HOLDING WAFER | VERHAVERBEKE, STEVEN |

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| 09891890 | Not Issued | 161 | 06/25/2001 | METHOD AND APPARATUS FOR FRONTSIDE AND BACKSIDE WET PROCESSING OF A WAFER | VERHAVERBEKE, STEVEN |
|----------|-----------|-----|-----------|---------------------------------------------------------------------------|----------------------|
| 09891849 | Not Issued | 071 | 06/25/2001 | METHOD AND APPARATUS FOR WAFER CLEANING | VERHAVERBEKE, STEVEN |
| 09891833 | Not Issued | 071 | 06/25/2001 | METHOD AND APPARATUS FOR CHEMICAL MIXING IN A SINGLE WAFER PROCESS | VERHAVERBEKE, STEVEN |
| 09891829 | Not Issued | 041 | 06/25/2001 | METHOD AND APPARATUS FOR DISSOLVING A GAS INTO A LIQUID FOR SINGLE WET WAFER PROCESSING | VERHAVERBEKE, STEVEN |
| 09891791 | Not Issued | 161 | 06/25/2001 | WAFER SPRAY CONFIGURATIONS FOR A SINGLE WAFER PROCESSING APPARATUS | VERHAVERBEKE, STEVEN |
| 09891730 | Not Issued | 071 | 06/25/2001 | CLEANING METHOD AND SOLUTION FOR CLEANING A WAFER IN A SINGLE WAFER PROCESS | VERHAVERBEKE, STEVEN |
| 09891259 | Not Issued | 164 | 06/25/2001 | METHOD AND APPARATUS FOR REMOVING ADHERED MOISTURE FORM A WAFER | VERHAVERBEKE, STEVEN VERHAVERBEKE |
| 09843229 | 6524940 | 150 | 04/26/2001 | METHODS AND DEVICES UTILIZING THE AMMONIUM TERMINATION OF SILICON DIOXIDE FILMS | VERHAVERBEKE, STEVEN |
| 09805348 | 6491763 | 150 | 03/13/2001 | PROCESSES FOR | VERHAVERBEKE, |

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| | | | | TREATING ELECTRONIC COMPONENTS | STEVEN |
|---|---|---|---|---|---|
| 09755720 | Not Issued | 161 | 01/04/2001 | RINSING SOLUTION AND RINSING AND DRYING METHODS FOR THE PREVENTION OF WATERMARK FORMATION ON A SURFACE | VERHAVERBEKE, STEVEN |
| 09727661 | Not Issued | 161 | 12/01/2000 | APPARATUS FOR PROVIDING OZONATED PROCESS FLUID AND METHODS FOR USING SAME | VERHAVERBEKE, STEVEN |
| 09603792 | Not Issued | 161 | 06/26/2000 | MEGASONICS APPLICATED ON THE BACKSIDE AND GOING THROUGH THE WAFER | VERHAVERBEKE, STEVEN |
| 09574790 | Not Issued | 161 | 05/19/2000 | METHODS FOR WET PROCESSING ELECTRONIC COMPONENTS HAVING COPPER CONTAINING SURFACES | VERHAVERBEKE, STEVEN |
| 09495399 | Not Issued | 161 | 01/31/2000 | WET PROCESSING METHODS FOR THE MANUFACTURE OF ELECTRONIC COMPONENTS USING LIQUIDS OF VARYING DENSITY | VERHAVERBEKE, STEVEN |
| 09478094 | 6517636 | 150 | 01/05/2000 | METHOD FOR REDUCING PARTICLE CONTAMINATION DURING THE WET PROCESSING OF SEMICONDUCTOR SUBSTRATES | VERHAVERBEKE, STEVEN |

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| | | | | | |
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| 09456585 | Not Issued | 161 | 12/08/1999 | METHOD FOR PREPARING SILICON SURFACES FOR HEMISPHERICAL GRAIN GROWTH | VERHAVERBEKE, STEVEN |
| 09253157 | Not Issued | 161 | 02/19/1999 | METHODS OF WET PROCESSING ELECTRONIC COMPONENTS USING PROCESS LIQUIDS WITH CONTROLLED LEVELS OF GASES | VERHAVERBEKE, STEVEN |
| 08684543 | 6132522 | 150 | 07/19/1996 | WET PROCESSING METHODS FOR THE MANUFACTURE OF ELECTRONIC COMPONENTS USING SEQUENTIAL CHEMICAL PROCESSING | VERHAVERBEKE, STEVEN |

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## Application Number Information

Application Number: **60/214054** <u>Order This File</u>  <u>Assignments</u>

Examiner Number: **00000** /

Filing Date: **06/26/2000**

Group Art Unit: **0000**

Effective Date: **06/26/2000**

Class/Subclass: **/.**

Application Received: **06/28/2000**

Lost Case: **NO**

Patent Number:

Interference Number:

Issue Date: **00/00/0000**

Unmatched Petition: **NO**

Date of Abandonment: **00/00/0000**

<u>L&R Code:</u> Secrecy Code:**1**

Attorney Docket Number: **4733/TCG/OTHER/LE**

Third Level Review: **NO**     Secrecy Order: **NO**

Status: **159 /PROVISIONAL APPLICATION EXPIRED**

Status Date: **08/31/2003**

Confirmation Number: **3634**

Oral Hearing: **NO**

Title of Invention: **ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS**

| Bar Code | PALM Location | Location Date | Charge to Loc | Charge to Name | Employee Name | Location |
|---|---|---|---|---|---|---|
| 60214054 | 9200 | 06/04/2001 | No Charge to Location | No Charge to Name | LOE CONV DR1995U | |

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## PALM INTRANET

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## Application Number Information

Application Number: **10/616093**
**Assignments**

Examiner Number: **00000 /**

Filing Date: **07/08/2003**

Group Art Unit: **1746**          **IFW IMAGE**

Effective Date: **07/08/2003**

Class/Subclass:
**134/033.000**

Application Received: **07/10/2003**

Lost Case: **NO**

Patent Number:

Interference Number:

Issue Date: **00/00/0000**

Unmatched Petition: **NO**

Date of Abandonment: **00/00/0000**

L&R Code: Secrecy Code:**1**

Attorney Docket Number: **4733 USA
D01/TCG/TPG/OTHE**

Third Level Review: **NO**          Secrecy Order: **NO**

Status: **20 /APPLICATION DISPATCHED FROM PREEXAM,
NOT YET DOCKETED**

Status Date:
**10/06/2003**

Confirmation Number: **9641**

Oral Hearing: **NO**

Title of Invention: **ASSISTED RINSING IN A SINGLE WAFER CLEANING PROCESS**

| Bar Code | PALM Location | Location Date | Charge to Loc | Charge to Name | Employee Name | Location |
|----------|---------------|---------------|---------------|----------------|---------------|----------|

**Appln Info**   | Contents | | Petition Info | | Atty/Agent Info | | Continuity Data | | Foreign Data |

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